

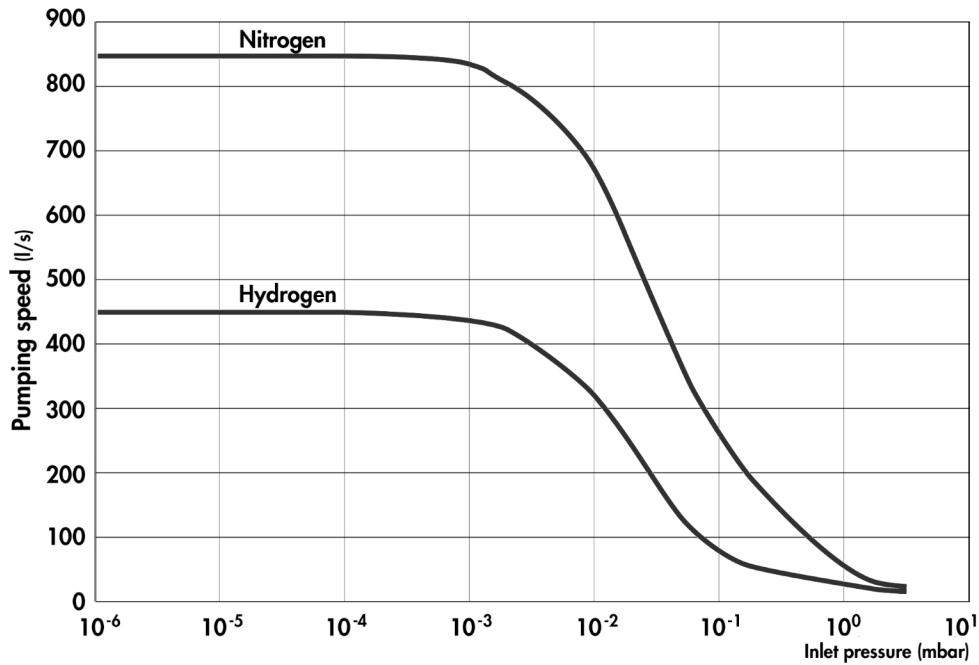


## Alcatel ATH-1000M Technical Specifications

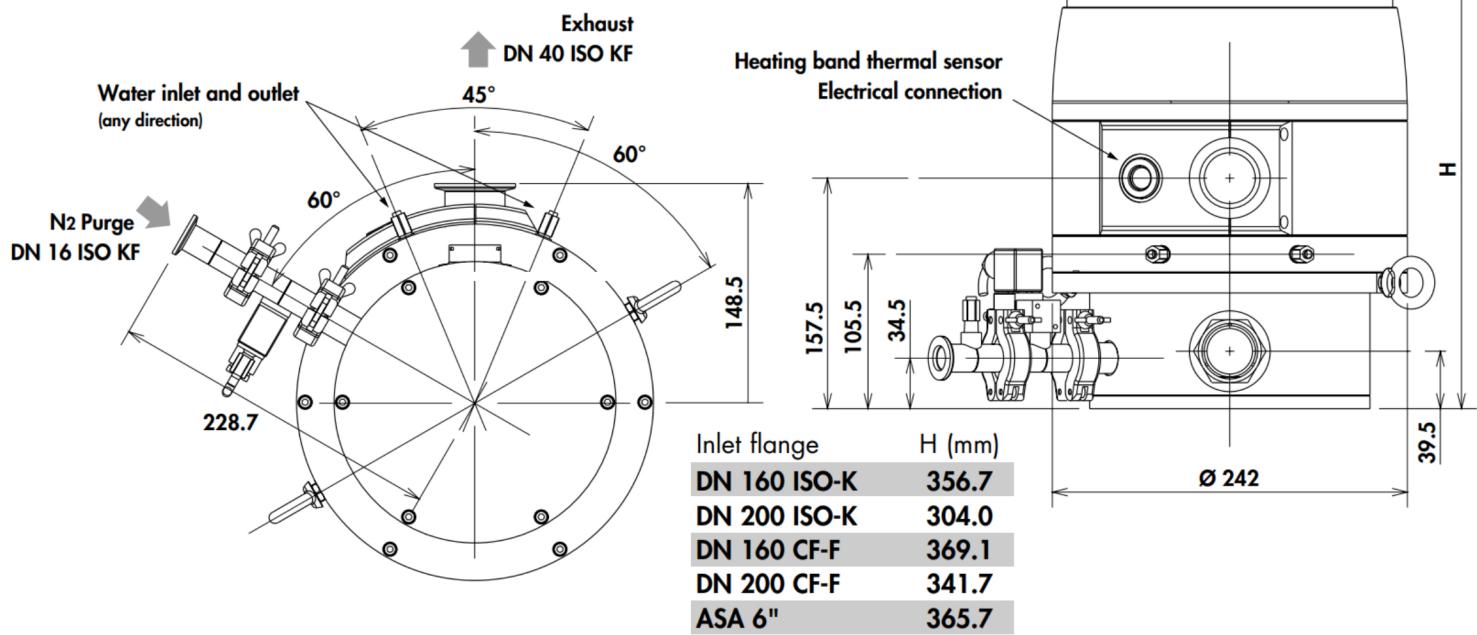
Model characteristics		ATH 1000M		ATH 1000MT	
Inlet flange	DN	160 ISO-K	200 ISO-K	160 ISO-K	200 ISO-K
Rotation speed	rpm	33000		30000	
Pumping speed*	N <sub>2</sub>	710 l/s	850	610	800
	He	650 l/s	750	600	650
	H <sub>2</sub>	430 l/s	450	330	350
Compression rate*	N <sub>2</sub>	2x10 <sup>+8</sup>			
	He	1x10 <sup>+4</sup>			
	H <sub>2</sub>	4x10 <sup>+2</sup>			
Ultimate pressure without purge, meas. according to Pneurop standard	mbar	8x10 <sup>-9</sup>			
Maximum pressure at inlet in continuous operation**	mbar	1x10 <sup>-1</sup>			
Maximum permissible pressure at exhaust**	mbar	5			
Noise level	dBA	≤ 39			
Start-up time	min	< 5			
Maximum start-up power	W	650			
Maximum operating power	W	300			
N <sub>2</sub> purge flow rate	SCCM	50			
Cooling water flow rate	l/h	< 60			
Water temperature	°C	15 < T < 25°C			
Maximum ambient temperature	°C	40			
Weight	kg	28			
Recommended forepump		ADP 81			



## Alcatel ATH-1000M Pumping Curves



## Dimensions





## Alcatel ATH-1000M

### Features & Benefits

- magnetically levitated
- automatic balancing system
- inert gas purge
- high throughput
- quiet & clean vacuum
- corrosion proof
- maintenance free
- easy integration
- battery free
- minimum size, weight & volume
- smart & compact electronic controller
- inverted dynamic seal creates high compression ratio



### Applications

- semiconductor • plasma etching • ion implantation • sputtering
- plasma deposition • electron microscopes • surface analysis
- research & development • high energy physics • space simulation • accelerators